

CY-083型抗电磁干扰动态压力传感器**CY-083 Anti Electromagnetic Interference Dynamic Pressure Sensor****1.工作原理**

CY-083型抗电磁干扰动态压力传感器是利用硅压阻效应原理，采用矩形双岛硅膜片结构，利用半导体平面工艺和硅微机械加工技术制作而成。

2.特点

抗电磁干扰动态压力传感器具有体积小、重量轻、抗干扰、频响高、性能可靠等特点。

3.应用范围

航天、航空及各类自动控制系统中。

1. Working Principle:

Working Principle of CY-083 anti electromagnetic interference dynamic pressure sensor is silicon piezoresistive effect. It is fabricated in structure of rectangular silicon double island diaphragm adopting semiconductor planar technology and silicon micromachining technology.

2. Characteristic:

Anti electromagnetic interference dynamic pressure sensor has characteristics of small volume, light weight, anti-jamming, high frequency response, reliable performance, etc

3. Application:

Application in the aerospace, aviation, and all kinds of automatic control system.



图 Picture CY-083